

Cambridge University Press

978-1-107-41416-7 - Materials Research Society Symposium Proceedings: Volume 583:

Self-Organized Processes in Semiconductor Alloys

Editors: Angelo Mascarenhas, David Follstaedt, Tohru Suzuki and Bruce Joyce

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**MATERIALS RESEARCH SOCIETY
SYMPOSIUM PROCEEDINGS VOLUME 583**

Self-Organized Processes in Semiconductor Alloys

Symposium held November 29–December 2, 1999, Boston, Massachusetts, U.S.A.

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Materials Research Society
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CAMBRIDGE UNIVERSITY PRESS

Cambridge, New York, Melbourne, Madrid, Cape Town,
Singapore, São Paulo, Delhi, Mexico City

Cambridge University Press

32 Avenue of the Americas, New York NY 10013-2473, USA

Published in the United States of America by Cambridge University Press, New York

www.cambridge.org

Information on this title: www.cambridge.org/9781107414167

Materials Research Society

506 Keystone Drive, Warrendale, PA 15086

<http://www.mrs.org>

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First published 2000

First paperback edition 2013

Single article reprints from this publication are available through
University Microfilms Inc., 300 North Zeeb Road, Ann Arbor, MI 48106

CODEN: MRSPDH

ISBN 978-1-107-41416-7 Paperback

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This work was supported in part by the Army Research Office under Grant Number ARO: DAAD
19-99-1-0359. The views, opinions, and/or findings contained in this report are those of the
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